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P A T E N T & T R A D E M A R K O F F I C E

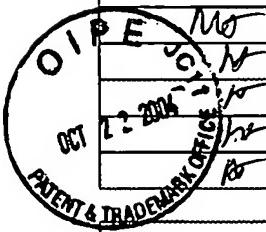
WILMER CUTLER PICKERING HALE AND DORR LLP SUBT. FORM PTO-1449				DOCKET NUMBER 02955.247	APPLICATION NUMBER 10/662,895
INFORMATION DISCLOSURE IN AN APPLICATION				APPLICANT Martin et al.	
(USE SEVERAL SHEETS IF NECESSARY)				FILING DATE September 15, 2003	GROUP ART UNIT 2811
SHEET	1	OF	3		

U.S. Patent Documents						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>Mos</i>	4,276,533*	06-1981	Tominaga et al.	338	4	
	4,700,973	10-1987	Gademann et al.	280	735	
	4,812,896*	03-1989	Rothgery et al.	174	52.4	
	4,829,822	05-1989	Imai et al.	73	516	
	4,862,245	08-1989	Pashby et al.	357	70	
	4,891,984*	01-1990	Fujii	73	517	
	4,894,698*	01-1990	Hisikigawa	257	254	
	4,906,586*	03-1990	Blackburn	257	254	
	4,922,756	05-1990	Henrion	73	517	
	4,965,654	10-1990	Karner et al.	357	70	
	5,006,487	04-1991	Stokes	437	228	
	5,044,201*	09-1991	Farace	73	503	
	5,086,018	02-1992	Conru et al.	437	207	
	5,090,254*	02-1992	Guckel	73	862.59	
	5,121,180*	06-1992	Beringhouse et al.	357	26	
	5,126,813	06-1992	Takahashi et al.	357	26	
	5,164,328*	11-1992	Dunn	437	54	
	5,181,156*	01-1993	Gutteridge	361	283	
	5,185,498	02-1993	Sanftleben et al.	174	52.2	
	5,185,653*	02-1993	Switky et al.	257	729	
	5,216,490*	06-1993	Greiffer et al.	257	659	
	5,310,450	05-1994	Offenberg et al.	156	630	
	5,323,051*	06-1994	Adams	257	417	
	5,376,588*	12-1994	Pendse	156	293	
	5,406,117*	04-1995	Drugokecki et al.	257	659	
	5,428,242*	06-1995	Furuya et al.	257	659	
	5,486,720*	01-1996	Kierse	257	659	
	5,629,559*	05-1997	Miyahara	257	666	
<i>Mos</i>	5,659,950	08-1997	Adams et al.	29	827	

EXAMINER <i>Mark W. G.</i>	DATE CONSIDERED <i>1/4/05</i>
EXAMINER: Initial if citation is considered, whether or not citation is in conformance with MPEP § 609: Draw Line through citation if not conformance and not considered. Include copy with next communication to applicant.	

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SHEET	2	OF	3	FILING DATE September 15, 2003	GROUP ART UNIT 2811

Foreign Patent Documents							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
O P E M	0 618 450*	5-1994	EP				
O P E M	0 646 798*	5-1995	EP				
O P E M	0 363 003	08-1989	EP				
O P E M	03120849 A*	05-1991	JP				
O P E M	1232267	09-1989	JP				



Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)		
MA	A1*	Adams, V. et al., "Low Cost Packaging for Accelerometers," <i>Electronic Packing and Production</i> , Vol. 33, No. 12, pp. 44-45 (1993)
1	A2*	<i>IFEE Transactions on Electron Devices</i> , "A Batch-Fabricated Silicon Accelerometer," Vol. Ed-26, No. 12 (1979)
	A3*	<i>IFEE Transactions on Electron Devices</i> , "A Monolithic Capacitive Pressure Sensor with Pulse-Period Output," Vol. Ed-27, No. 5 (1980)
	A4*	<i>Sensors and Actuators</i> , "A Micromechanical Capacitive Accelerometer with a Two-Point Inertial-Mass Suspension," Vol. 4, pp. 191-198 (1983)
	A5*	<i>Sensors</i> , "Understanding Silicon Accelerometers," Sept. (1989)
	A6*	<i>Sensors</i> , "Micromachined Sensors for Automotive Applications," Sept. (1991)
	A7	"Motorola Develops Rugged New Accelerometer," Press Release, Motorola Inc., Oct. 1992.
	A8	Gardner, Dana, "Motorola broadens scope of sensors products," <i>Design News</i> , July 1992.
	A9	Yun, Weijie and Howe, Roger T., "Recent Developments in Silicon Microaccelerometers, <i>Sensors</i> , October 1992.
	A10	"Three-Plate Capacitor is Transformed into a Microaccelerometer," <i>Sensors</i> March 1993.
PA	A11	Adams, V., Frank, R., and Hughes, H., "Low Cost Packaging For Accelerometers," <i>Electronic Packaging &amp; Production</i> , Dec. 1993.

EXAMINER	DATE CONSIDERED
<i>Dawn A. Ettinger</i>	<i>1/4/05</i>

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Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)					
16	A12	Ajluni, Cheryl, "Silicon Accelerometer Targets Airbag Restraint Systems," <i>Electronic Design</i> , October 1995.			
	A13	Terry, S., "A miniature Silicon Accelerometer with Built-in Damping," IEEE Solid-State Sensor and Actuator Workshop, June 1988.			
	A14	de Bruin, D., Allen, H., Terry, S., "Second-order Effects in Self-testable Accelerometers" IEEE Solid-State Sensor and Actuator Workshop, June 1990			
	A15	Alan, H., Terry, S., and Knutti, J., "Understanding Silicon Accelerometers," <i>Sensors</i> , September 1989.			
	A16	"Silicon Accelerometers," <i>IC Sensors</i> , Technical Note TN-008 (no date).			
	A17	Allen, H., Terry, S., de Bruin, D., "Accelerometer Systems with Built-in Testing," <i>IC Sensors</i> , 1989.			
	A18	Peeters, E., Vergote, S., Puers, B., and Sansen, W., "A Highly Symmetrical Capacitive Micro-Accelerometer with Single Degree-of-Freedom Response," International Conference on Solid-State Sensors and Actuators, 1991.			
	A19	Henrion, W., DiSanza, L., Ip, M., Terry, S., and Jerman, H., "Wide Dynamic Range Direct Digital Accelerometer," IEEE Solid-State Sensor and Actuator Workshop, June 1990.			
	A20	Ristic, L., Gutteridge, R., Dunn, B., Mietus, D., and Bennet, P., "Surface Micromachined Polysilicon Accelerometer," IEEE Solid-State Sensor and Actuator Workshop, June 1992.			
	A21	Ristic, L., Gutteridge, R., Kung, J., Koury, D., Dunn, B., and Zunio, H., "A Capacitive Type Accelerometer with Self-Test Feature Based on a Double-Pinned Polysilicon Structure," 7 <sup>th</sup> International Conference on Solid-State Sensors and Actuators, June 1993.			
	A22	Ristic, L. (editor), <i>Sensor Technology and Devices</i> , (pages 234-237), 1994.			
16	A23	Li, G. and Tseng, A., "Low Stress Packaging of a Micromachined Accelerometer," <i>IEEE Transactions on Electronics Packaging Manufacturing</i> , Vol. 24, No. 1, January 2001.			

EXAMINER	DATE CONSIDERED
<i>Matthew C. G.</i>	11/4/05
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